



Docket No. 51380

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

**APPLICANT:** Takashi et al.

**SERIAL NO.** 10/078,766 **GROUP:** 1742

**FILED:** February 19, 2002 **EXAMINER:** W. Leader

**FOR:** PROCESS FOR ELECTROPLATING SILICON WAFERS

Mail Stop: RCE  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

**AMENDMENT**

Applicants file herewith a Request for Continued Examination (RCE). Please amend the application as follows.

A listing of pending claims begins on page 2 of this paper.

Remarks begin on page 4 of this paper.